



Integrated Nano-Photonics: The Transition to High-Volume Manufacturing and Implications for Workforce Education

Robert Geer

Professor and PI NSF NEATEC ATE Center AIM Photonics (Manufacturing USA Institute) College of Nanoscale Science & Engineering SUNY Polytechnic Institute



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Introductions







Mike Lesiecki, host

Atilla Ozgur Cakmak, NACK Network

Robert Geer, Professor of Nanoscale Science













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Outline:

- Integrated Nano-Photonics Manufacturing (**IPM**): Overview & comparison with ICs
- Photonic Integrated Circuits (**PIC**s) Turning the corner on high-volume manufacturing
 - Key manufacturing advances
 - Design ecosystem
 - Foundry model
- Skills and Tasks for IPM Technicians
 - PICs vs ICs
 - Assembly & Test
 - Packaging
- Tech Education Modules
 - PIC Testing
 - PIC Wafer-scale/Chip-Scale QC
 - Advanced Packaging (2.5D/3D) Assembly)









Before Getting to Integrated Nano-Photonics Manufacturing...

A Little History on Integrated Circuits









Historical Perspective – Integrated Circuits

- 1961 and 2018 integrated circuits.
- Progress due to:
 - Feature size reduction 0.7X/3 years (Moore's Law)
 - New Materials conductors, dielectrics, semiconductors
 - New Devices/Designs FinFETs, Al-specific designs





First Planar Integrated Circuit 1961: *4 Transistor* Flip-Flop IBM 7nm Node Chip 2018: 20 Billion Transistors









Historical Perspective – IC-Enabled Systems



Original data up to the year 2010 collected and plotted by M. Horowitz, F. Labonte, O. Shacham, K. Olukotun, L. Hammond, and C. Batten New plot and data collected for 2010-2015 by K. Rupp







And then there's photonics...

"The physical science of light (photon) generation, detection, and manipulation through emission, transmission, modulation, signal processing, switching, amplification, and sensing."









Fiber Optics – Revolutionizing Communication



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Photonics Systems – Driven by Discrete Components

- In telecommunications discrete photonics components have dramatically increased data transmission
 - Sources (infra-red lasers)
 - Interconnects (fibers)
 - Detectors (PIN diodes)
 - Encoders (modulators)







• Wavelength division multiplexing dramatically increases data rates







Integrated Photonics – Sources, Devices, and Detectors on a Single Chip









But First a Poll Question

What is the difference between Photonics and Integrated Nano-Photonics?

- a) Integrated Nano-Photonics refer to photonic devices integrated on a single chip.
- b) Integrated Nano-Photonics don't include waveguides or fiber optics.
- c) Integrated Nano-Photonics always include transistors.









Another Poll Question

In the context of Integrated Nano-Photonics what does PIC stand for?

a) Abbreviation for 'Picture'

b) Abbreviation for 'Photonic Integrated Circuit'

c) Abbreviation for 'Positive Index Contrast'







Adapt Si-based IC Methodology to Integrate Photonics Components



Photonic device & interconnect design and layout

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Fabrication of Si-based photonic devices (SEM of Si modulator)

- Photonic Integrated Circuits (PICs) combine:
 - On-chip Si waveguides (e.g. fibers)
 - Devices (e.g. modulators)
 - Light sources (lasers)
 - I/O structures



(with laser attached)

Electro Optical test of PIC chip



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PICs: Transition to High-Volume Manufacturing (HVM)

- Why now?
 - Key Manufacturing Advance: Lithography
 - PICs not practical before 193nm immersion litho



Isolated

Line

16nm

35 nm

40 nm

1:1

50 nm

ASMI

TWINSCAN NXT:1950i 193-nm Step & Scan Photo: ww.asml.com

		Tool type	Dense L/S (1:
	<u>EUV</u>	ASML 3300B	<u>18nm</u>
+-+-	<u>193nm</u>	ASML 1950i	<u>42 nm</u>

Immersion ASML 1700i



TWINSCAN NXE:3300B Photo: www.asml.com



Dense

25nm

60 nm

70 nm

Via



- Electronic and photonic design/codesign – Requires CAD infrastructure
 - Enables widespread PIC design workforce
 - Allows designers to build on established IP
- Full 300mm wafer fabrication and test infrastructure (wafer & die)
 - Rapid prototyping and optimization
 - 'Foundry' model to enable broad adoption of PIC solutions
- Interposers & chip attach
 - Integration with IC's
 - Laser attachment and packaging





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HVM: Integrating PICs with ICs



Vertical integration of an electronic IC (EIC) driver-chip on top of a Si-PIC

- (a) EIC integrated on a PIC, with RF (radio frequency) and DC (direct current) signals routed from front-end electronics on the PCB
- (b) EIC integrated onto the PIC using discrete copper-pillar-bumps (CPBs)
- (c) Image of interconnects between the EIC and PIC.









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Poll

Which statement is true about Integrated Nano-Photonics?

- a) Integrated Nano-Photonics products won't be introduced to the market until the next decade.
- b) Integrated Nano-Photonics products are in the market now.
- c) It is unlikely that Integrated Nano-Photonics products will ever make it to market.







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Key PIC Technologies

PIC Sensors

- Improved healthcare
- Threat mitigation
- Spectroscopy
- Low cost and disposable

Data Comm / Telecom

- Connect the world
- More energy efficient
- □ 400Gbs, 800Gbs, 2.56Tbs
- Protect the environment

RF over Fiber

Lighter, faster, less power required

- □ More compact and cost effective
- □ Multiple sources of info in one fiber
- Quick adaptability to requirements



Microfluidics to enable real-time detection of biological substances such as protein biomarkers of human stress and traumatic brain injury.



Increase performance of server farms while decreasing energy consumption and simultaneously expanding global communication.



With fiber optic cabling, users can add other optical wavelengths resulting in multiple sources of information on one fiber which allows much quicker reaction to changes in environment and requirements.









PIC Technologies in the Market













Questions on PIC & IPM Intro and Overview?









Integrated Nano-Photonics Manufacturing (IPM): Workforce Skills & Competencies









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Task

Specialization

IPM: Workforce Implications

IP	M Manufacturing Path	Workforce Education Prep
•	R&D	B.S./M.S./Ph.D.
•	PIC Design & Sim	B.S./M.S./Ph.D. → A.S/A.A.S.?
•	PIC Manufacturing	A.A.S./B.S. (some M.S./Ph.D)
•	PIC Assembly (KGD Test)	A.A.S./B.S.
•	PIC Packaging	A.A.S. (some B.S.)
ŀ	Testing/Quality Control	A.A.S.

- Dominated by 2-yr degrees
- Substantial Overlap with IC Techs
- Some Overlap with IC Techs and Photonics Techs
- Substantial Overlap with Photonics Techs



R&D

Product





A Semiconductor Manufacturing Technician Knows:	Knowledge and Skills Needed as an IPM Technician	
 The semiconductor manufacturing process (Si-ICs) Automated materials handling systems (mechanical/electrical components) Automated fabrication systems (fluid power, PLCs, robotics) Cleanroom protocols Vacuum and RF technology Metrology, SPC, and quality control Data Integrity, encryption and data security 	 Light sources (lasers) particularly VCSELs Waveguides and waveguide loss measurements Detectors and detector response measurements Basic optical characterization Electro-optic characterization of PICs Interposer assembly IC attachment (3D stacking) PIC and interposer packaging Fiber attach Testing and reliability 	



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PIC Testing and Specialized Assembly/Packaging



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Types of IPM Technicians: First Pass Skills Analysis

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Overlap

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• "Fab" Equipment Technician

- Maintenance, troubleshooting, upgrades and installations of vacuum and cleanroom equipment.
- Maintenance, troubleshooting, upgrades and installation of automated processing, control and transportation equipment.
- Nanotech equipment maintenance and operation.

Integrated Photonics Test, Assembly & Packaging Techs

- Operation and maintenance of equipment to test PIC wafers; interpret results
- PIC assembly (die to interposer/laser attach/IC to interposer attach)
- Operation and maintenance of equipment to test PIC assemblies (die-interposer) and interpret results
- PIC packaging (PCB-level package, fiber attach, sensor package)
- Operation and maintenance of equipment to test packaged systems









IPM Test, Assembly and Packaging



Wafer-scale Photonics Packaging

- Wafer-scale testing (Opt/RF/DC)
- PIC & Interposer Metallization
- Die bonding (laser & PIC)
- Singulation of die

Chip-scale Test, Assembly and Packaging

- Chip Scale Testing (*Opt/RF/DC*)
- Fiber and Laminate attach
- Surface Mount Assembly











Examples of Critical Work Functions for IPM Test, Assembly & Packaging Techs (Chip-Scale)

- 1. Clean, Mount, Inspect & Prepare PIC chips for Testing
- 2. Operate, maintain, and calibrate instrumentation to test PIC chips
- 3. Conduct tests of PICs, record data, interpret & report results once die is mounted and connected to test station.
- 4. PIC Alignment, Assembly, and Packaging
 - a. 2D, 2.5D and 3D Alignment and Assembly of PICs
 - b. Assemble and package PIC stacks into workable IP components
- 5. Prepare and connect component packages for testing.
- 6. Operate, maintain, modify, calibrate, troubleshoot and repair instrumentation to test assembled components.
- 7. Conduct tests of assembled components, record data, interpret and report results.
- 8. Conduct long-term system performance testing and failure analysis.





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Critical Work Function #4a for IP Test/Assembly Techs

2D, 2.5D and 3D Alignment and Assembly of PICs.

Task A

Alignment and 3D Bonding of ASIC die on PIC die

- Operate micro-optic pick/place equipment for ASIC or memory die on PIC die
- Perform bonding/attachment and/or under-fill between die

Task B

Alignment and Bonding of various die on passive or active interposer.

- Operate micro-optic pick/place equipment for PIC die on passive or active interposer
- Operate micro-optic pick/place equipment for ASIC or memory die on passive or active interposer
- Operate micro-optic pick/place equipment for IR laser sources on passive or active interposer
- Perform bonding/attachment and/or under-fill between die and interposer

Task C

3D inspection of full die stack or die/interposer stack.









Assemble and package PIC stacks into workable IP components.

- **Task A** Place PIC interposers into optical package.
- **Task B** Setup components for precision alignment.
- **Task C** Wire bonding for electrical control signals.
- **Task D** Create optical fiber connections.
- **Task E** 3D inspection of fiber alignment/connection.

Task F - Verify final package connection integrity and troubleshoot as needed.





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Where do IPM Tech Skills Fit?









IPM Educational Module Design: Technician Competency Model

• Basic DOL Technician Competency Blueprint:

IPM program focused on mid-range tiers: 4-6







Competency Model Template (US DOL)

Industry Sector: Semiconductor Manufacturing and IPM

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- Previously undeveloped for Semiconductor Mfg and IPM
- Build on existing models (e.g. MATEC & SEMI/Sematech)

Industry-wide: Advanced Manufacturing

- Sufficient foundational skills?
- Data literacy?
- Intro to 'Design Concepts'?









Questions on PIC & IPM Tech Skills?









IPM Tech Education Module Design: Course/Module Tier Designations

• IPM Course Elements and Technician Competency Tier

IPM Modules	Technician
	Competency Tier
1. General IPM technology overview modules: e.g. basic IPM concepts and	Tier 2
IPM applications	
2. Process basics 1: Underlying topics and skills associated with the base IP fab	Tier 4
process	
3. Process basics 2: compound process basics that combine multiple	Tier 4
capabilities and skills	
4. Specific manufacturing process flow and systems modules: e.g. Si-based IP	Tier 5
manufacturing process flow and key IP processing modules	
5. Assembly, metrology/test, and quality control modules: e.g. 2.5D/3D IP	Tier 5
assembly, basic performance testing of on-chip IP devices, etc	
6. Practical training courses (Internships, capstone experiences at IPM-	Tier 6
equipped facilities): e.g. 300mm Si fabrication cleanroom process operator	
internship (currently in place at SUNY Poly)	









IPM Technician Test Chip for IPM Technician Education Modules



Non-proprietary IPM test structures (SUNY Poly)

IP wafer on NEATEC test station

- Passive test structure development (Chipsets #1) development/fab completed
- Designed for use with NEATEC test station in NEATEC user facility







NEATEC IPM: Technician Task Example

- <u>Technician Task</u>: 'Cut-back' loss measurement for on-chip waveguides. Determine optical loss (dB/cm) and compare with design spec
- Key Skills:

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- Die/wafer place
- Probe align
- Data acquisition
- Collate/document
- Hands-on element for:
 - Wafer-scale PIC Testing
 - Chip-scale PIC Testing









• Skill Example: Probe Align

- Probe align for Si waveguide measurement (loss)
- Probe configuration
- Power optimization
- Hands-on element for:
 - Wafer-scale PIC Testing
 - Chip-scale PIC Testing





Probe Configuration: 1



Probe Configuration: 2

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- <u>Skill Example: Data Acquisition/Collation/Documentation</u>
 - Multi-power data acquisition
 - Collation/documentation (data port to plot & analysis)
 - Document for engineer team report
- Hands-on element for:

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- Wafer-scale PIC Testing
- Chip-scale PIC Testing

State of Art: IP waveguide **NEATEC IPM Lab Measurement:** 1.4 -25 0.003uW 0.004i/W -30 1.2 Transmission [dB] 450nm 0.009-0 -35 0.01uW 0.011.W 1.0 -40 Power 0.8 -45 -50 -1.84 (±0.1) dB/cm -1.57 (± 0.09) dB/cm 0.6 -55 0.4 -60 5 0 15 20 10 2.0 2.5 3.0 3.5 4.0 4.5 5.0 spiral length [cm] Length(cm)



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IPM Practical Training Modules: Device Measure and Quality Control

- IPM Test Tech User Interface Development
 - Standard IP passive device measure (waveguides, RRs, couplers, MZIs)
 - Custom interface developed to support 2-year college student training
 - Result of Spring '18 workshop with FMCC students









Additional Testing Protocols:

- **<u>Technician Tasks</u>**: Testing protocols for basic passives/actives
- Passive Elements:
 - Couplers
 - Gratings
 - Resonators
 - Filters/splitters
- Hands-on element for:
 - Wafer-scale PIC Testing
 - Chip-scale PIC Testing
- <u>Chipset #1:</u>
 - Completed and testing protocols developed









Passive and Active IP Device Fab for IP Tech Practical Training

- Devices for Technician Practical Training: Chipset #2
 - Standard IP passive devices (waveguides, RRs, couplers, MZIs)
 - Integrate onto 'dice'-able test structures for mounting into simple package
 - 2018/2019 passive multi-project wafer (MPW) runs completed





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IPM Practical Training Modules: Device Measure and Quality Control

- Within-wafer non-uniformity (WIWNU) for IP Ring Resonators
 - Module completed in 2018/2019
 - Spreadsheet based (utilized IPM Probe Station)







SU Update – Passive and Active IP Device Fab for IP Tech Practical Training

- Devices for Technician Practical Training: Chipset #3
 - Standard IP active devices (modulators and detectors)
 - Integrate onto 'dice'-able test structures for mounting into simple package
 - 2019 one active multi-project wafer (MPW) run completed









3D/2.5D Semiconductor Manufacturing Curricular Development





3D/2.5D IC Lecture Content for Tool Tech Training Modules

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3D/2.5D Chip Stacking and Interposer Introduction for Assembly, Metrology & Tool Techs:

- Collaborated with CNSE faculty (Dr. Ernie Levine) on overview content for '3D/2.5D IC' fabrication
- Provide as introduction for fabrication, test, and assembly techs (for IPM)

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2.5D/3D IP Assembly: Practice Facility and Initial Modules

- 3D Die assembly inspection facility (IR alignment and fill inspect)
 - Basic module 'instruction manual' assembled
 - Utilized 3D die-to-wafer assembly
 - Die available for 2-yr college student workshops for 2019







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Summary and Next Steps

- Integrated Nano-Photonics is turning the corner towards HVM
 Design tools and initial foundry model in place (AIM Photonics, IMEC)
- IMP Tech Skills

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- PIC mfg skills → IC fab skills
- PIC assembly skills → bridges IC & photonics
- IP packaging/test skills photonics tech skills
- IMP Tech Education Module
- Development
 - Initial modules developed
 - Highly-reliant on IPM equipment
 - Need scaling model









Thank you! Q&A





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